Tentative Agenda for Workshop on Electron Beam Lithography (subject to change):

Note: the workshop will take place in the Seminar room on the second floor of the Center for Functional Nanomaterials (Building 735)

Tuesday (2/17):

9:45 am – Welcome/intro

10:00-10:45 Gerald Lopez/BEAMER I (GeniSYS)

10:45-11:00 coffee break

11:00-11:45 Gerald Lopez/BEAMER II (GeniSYS)

11:45-12:15 BEAMER Q&A

12:15-1:30 lunch break

1:30-2:00 Ming Lu

2:00-3:30 CFN User talks

3:30-4:00 optional CFN tour

Wednesday (2/18):

9:30 Welcome/intro

9:45-10:45 Luozhou Li (MIT)

10:45-11:00 coffee break

11-12 – Ryo Funakoshi (JEOL USA)

12-1:15 lunch break

1:15-1:45 Aaron Stein (CFN)

1:45-3:00 CFN user talks

3:00 coffee break

3:30 CFN User proposal info session (optional)